Leica Products





The Leica EM SCD500 is a versatile high vacuum film deposition system designed to produce very thin, fine-grained metal films and conductive carbon coatings for highest resolution FE-SEM analysis.

A versatile high vacuum oil-free film deposition system using a membrane diaphragm pump offering many options in a single unit; high vacuum sputtering, carbon thread, thermal resistance and carbon rod evaporation, cryo preparation for freeze drying, freeze fracturing/etching, double replica, cryo coating and vacuum cryo transfer with Leica EM VCT100. Interchangeable Vacuum chambers for different sample sizes and processes.

Planetary drive stage provides the best uniformity of the sputter deposition; Rotary and tilting stages achieve excellent shadowing affects and the stepless height adjustable specimen table gives defined film deposition with minimum specimen damage. Preselectable and permanently stored sputtering parameters Stepless height adjustable specimen table for defined film deposition with minimum specimen damage with preselectable and permanently stored sputtering parameters.

A built-in high voltage etching device for surface cleaning improves adhesion of the subsequent coating or makes carbon films hydrophilic.

\$535 EM SCD500 High vacuum coater